

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroyoshi TOMINAGA et al.

Application No.: New U.S. National Stage of  
PCT/JP03/03743

Filed: June 29, 2004

Docket No.: 120214

For: WAFER DOUBLE-SIDE POLISHING APPARATUS AND DOUBLE-SIDE  
POLISHING METHOD

PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Please consider the following:

**Amendments to the Specification;**

**Amendments to the Claims** as reflected in the listing of claims;

**Remarks.**